

IN THE UNITED STATES PATENT AND TRADEMARK OFFICE

Application of:

Applicant(s) :
Serial No. : 10/599,691
Filed : October 5, 2006
Title : METHODS FOR COATING A
SUBSTRATE AND FORMING
A COLORED FILM AND
RELATED DEVICE
Group :
Docket : CLB 003 P2 – BR 26743

Certificate of Submission

I hereby certify this paper is being submitted via
EFS on this 28th day of December, 2006 by
Tammy Frederick.

____ / Tammy Frederick / ____

Mail Stop Non-Fee Amendment
Commissioner for Patents
P.O. Box 1450
Alexandria, VA 22313-1450

Sir:

INFORMATION DISCLOSURE STATEMENT UNDER 37 CFR §1.97(b)

Pursuant to the provisions of 37 CFR §1.97(b), Applicant(s) wishes to disclose the materials listed below and on the attached form PTO/SB/08A which the Examiner may find relevant to the examination of the above-identified patent application. Pursuant to the Official Gazette Notice of August 5, 2003, copies of issued U.S. patents and/or U.S. patent applications are not required and are not enclosed. Copies of any foreign or non-patent reference materials are enclosed herewith.

<u>U.S. Patent No.</u>	<u>Issued</u>	<u>Inventor (s)</u>	<u>Title</u>
4,947,789	08/14/1990	Hussla et al.	APPARATUS FOR VAPORIZING MONOMERS THAT FLOW AT ROOM TEMPERATURE
5,069,930	12/03/1991	Hussla et al.	METHOD FOR THE EVAPORATION OF MONOMERS THAT ARE LIQUID AT ROOM TEMPERATURE
5,447,568	09/05/1995	Hayakawa et al.	CHEMICAL VAPOR DEPOSITION METHOD AND APPARATUS MAKING USE OF LIQUID STARTING MATERIAL
5,562,776	10/08/1996	Sapru et al.	APPARATUS FOR MICROWAVE PLASMA ENHANCED PHYSICAL/CHEMICAL VAPOR DEPOSITION
5,580,822	12/03/1996	Hayakawa et al.	CHEMICAL VAPOR DEPOSITION METHOD
5,970,908	10/26/1999	Glanz et al.	APPARATUS AND IMPROVED POLYMERIZATION GUN FOR COATING OBJECTS BY VACUUM DEPOSIT
6,004,885	12/21/1999	Hayakawa et al.	THIN FILM FORMATION ON SEMICONDUCTOR WAFER
6,475,563	11/05/2002	Hayakawa et al.	METHOD FOR FORMING A THIN FILM USING A GAS
6,790,475	09/14/2004	Yoo	SOURCE GAS DELIVERY

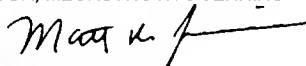
U.S. Publication Number	Date Published	Inventor(s)	Title
2002/0076489	06/20/2002	Hayakawa et al.	METHOD FOR FORMING A THIN FILM USING A GAS
2003/0190422	10/09/2003	Yoo	SOURCE GAS DELIVERY
2005/0028735	02/10/2005	Yoo	SOURCE GAS DELIVERY

The filing of this Information Disclosure Statement shall not be construed to be an admission that the information cited in the statement is, or is considered to be, material to patentability as defined in §1.56(b). By filing this statement, Applicant(s) is not making any representation as to whether any of the references referred to herein are material. Further, Applicant(s) cites these references without prejudice, and Applicant(s) reserves the right to contest the status of these references as prior art.

The Commissioner is hereby authorized to charge any additional fees under 37 C.F.R. 1.16 and 1.17 which may be required by this paper, or to credit any overpayment, to **Deposit Account No. 50-1287**. Applicant(s) hereby provides a general request for any extension of time which may be required at any time during the prosecution of the application. The Commissioner is also authorized to charge any fees which have not been previously paid for by check and which are required during the prosecution of this application to **Deposit Account No. 50-1287**. (Should Deposit Account No. **50-1287** be deficient, please charge any further deficiencies to Deposit Account No. 10-0220).

Respectfully submitted,

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